

Remarks

On November 19, 2003, an Office Action relating to the subject application was mailed. The Office Action rejected all pending claims in the subject application. Applicants respectfully traverse all rejections and respectfully request reconsideration of the pending claims in the subject application.

All of the claims have been rejected based on Xu et al. alone or in combination with other references. However, as understood, Xu et al. relates to laser imaging and spectral analysis system – and generally relates to the detection of defects in semiconductor wafers using both functions of laser imaging and spectral analysis. The present invention It will be shown that there are significant differences between the teachings of Xu et al. and the claimed subject matter.

Claims 10 and 18

Claim 10 was rejected under 35 USC 102(b) as being anticipated by Xu et al. It is well established that a reference cannot anticipate a claim unless every element and limitation recited in the presented claim is disclosed in the cited reference. In other words, the reference must teach every aspect of the claimed invention either explicitly or impliedly. Any feature not directly taught must be inherently present.

In the present matter, there are several differences between the invention as presented in independent claim 10 and the Xu et al. reference. Claim 10 of the present application recites:

An optical inspection system comprising

- a) a source of illumination emitting light in a first direction;*
- b) a mirror having a reflective surface positioned at an angle transverse to the first direction;*
- c) an inspection area illuminated by light reflected from the mirror;*
- d) a camera facing the inspection area; and*
- e) a means for absorbing extraneous light from the source of illumination passing through the mirror, said means positioned on a side of the mirror opposite the source of illumination.*

Among other differences, The Xu et al. reference does not teach nor disclose “a means for absorbing extraneous light from the source of illumination passing through the

mirror, said means positioned on a side of the mirror opposite the source of illumination”.

Any suggestion that the beam dump equates to the means for absorbing extraneous light and is positioned as required by the present claim, as taught by the present application is erroneous. Applicants kindly request reconsideration.

Claims 10 and 18 were also rejected under 35 USC 102(e) as being anticipated by Chiang. Again, in addition to other elements and features, Chiang fails to teach or disclose *“a means for absorbing extraneous light from the source of illumination passing through the mirror, said means positioned on a side of the mirror opposite the source of illumination”.*

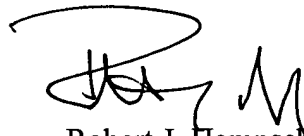
Claims 1-9 and 11-18

Claims 1-9 and 11-18 were rejected under 35 USC 103(a) as being unpatentable over Xu et al. in view of various secondary references. Applicants traverse this rejection for the same reasons outlined above. In addition, there is no teaching or suggestion to make the combinations suggested by the Office Action.

Conclusion:

Applicant contends that the application is now in condition for allowance. A notice to that effect is earnestly solicited.

Respectfully Submitted,

A handwritten signature in black ink, appearing to read 'R. Hampsch', with a large, stylized initial 'R'.

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In the Claims

2. (Amended) The optical inspection system of claim 1 wherein the light trap comprises a cylinder with a conical member disposed therein.